



Patent
Attorney's Docket No. 015290-502

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of)	
)	
Helen H. ZHU et al.)	Group Art Unit: 2823
)	
Application No.: 09/820,694)	Examiner: J. J. Maldonado
)	
Filed: March 30, 2001)	Confirmation No.: 7374
)	
For: METHOD OF PLASMA ETCHING)	
SILICON NITRIDE)	

AMENDMENT AFTER FINAL REJECTION

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Office Action mailed November 20, 2003, please amend the
above-identified application as follows:

do not
enter
09/27/2004
fee